

Title (en)
Vacuum pump arrangement

Title (de)
Vakuumpumpanordnung

Title (fr)
Unité de pompage à vide

Publication
EP 1447567 A3 20050615 (DE)

Application
EP 04000831 A 20040116

Priority
DE 10305038 A 20030207

Abstract (en)
[origin: EP1447567A2] A tempering device (20) is provided between a suction side flange (13) of a pump and a recipient connection flange (16).

IPC 1-7
F04D 19/04; **F04D 29/58**

IPC 8 full level
F04D 19/04 (2006.01); **F04D 29/58** (2006.01); **F04D 29/60** (2006.01)

CPC (source: EP US)
F04D 19/04 (2013.01 - EP US); **F04D 29/584** (2013.01 - EP US); **F04D 29/601** (2013.01 - EP US)

Citation (search report)

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- [XA] EP 1231383 A1 20020814 - SEIKO INSTR INC [JP]
- [XA] EP 0819856 A1 19980121 - VARIAN SPA [IT]
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Designated contracting state (EPC)
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IT LI LU MC NL PT RO SE SI SK TR

DOCDB simple family (publication)
EP 1447567 A2 20040818; **EP 1447567 A3 20050615**; **EP 1447567 B1 20070919**; AT E373781 T1 20071015; DE 10305038 A1 20040819; DE 502004004989 D1 20071031; JP 2004239258 A 20040826; US 2004156713 A1 20040812; US 7500821 B2 20090310

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EP 04000831 A 20040116; AT 04000831 T 20040116; DE 10305038 A 20030207; DE 502004004989 T 20040116; JP 2004007842 A 20040115; US 77175304 A 20040204